

Specification for the book of courses

Study program		Electrical Engineering and Computer Science			
Module		Common			
Type and level of studies		Doctoral studies			
The name of the course		Technology, Design and Characterization of Microsystems			
Lecturer (for lectures)		Prijić D. Zoran			
Lecturer/associate (for exercises)					
Lecturer/associate (for OFE)					
Number of ECTS	10	Course status (obligatory/elective)	Elective		
Prerequisites					
Course objectives					
The objectives of the course are such that a PhD student will:					
- Know the materials used in the production of microsystems;					
- Know the technological processes used for production;					
- Understand the process of designing and characterizing microsystems.					
Course outcomes					
Learning specific learning outcomes are defined so that a PhD student will:					
- Distinguish materials used in the production of microsystems;					
- Distinguish, at the level of detail, technological processes and their order in the production of microsystems;					
- Explain, at the level of detail, the process of designing and characterizing microsystems;					
- Design the microsystem, according to the given functional and technical specifications.					
Course outline					
Theoretical teaching					
Basic terms. Materials for microsystems - Materials in silicon technologies: monocrystalline silicon, polycrystalline silicon, silicon dioxide, silicon nitride, metal films, polymers. Materials in other technologies: silicon carbide, diamond, gallium arsenide and other III / V semiconductor compounds, piezoelectric ceramics. Material properties and physical effects. Technological processes in the production of microsystems - Standard technological processes: lithographic processes, thin layer deposition processes: CVD processes, PVD processes, Wet and dry etching. Other technological processes: anodic bonding, sol-gel deposition, electrolytic deposition. Technologies of Micro Machines. Surface micromachining, volume micromachining, LIGA, DXRL and EFAB technologies, assembling and integrating microsystems into enclosures. Flow diagram of microsystem design. Characterization of components and subsystems. Integration of analog and digital components of the microsystem. Microsystem power supply. Performance optimization.					
Practical teaching (exercises, OFE, study and research)					
Study research work in the field of materials, technological processes, design or characterization of microsystems, according to student affinity.					
Textbooks/references					
1	"MEMS: Fundamental Technology and Applications (Devices, Circuits, and Systems)", Ed. by V. Choudharu and K. Iniewski, CRC Press, 2013.				
2	Selected scientific papers (reviews)				
3	N. Maluf and K. Williams, "An Introduction to Microelectromechanical Systems Engineering", 2nd Ed., Artech House, 2004.				
4					
5					
Number of classes of active education per week during semester/trimester/year					
Lectures	Exercises	OFE	Study and research work	Other classes	
3	0	0	0	0	
Teaching methods					
Lectures; Consultations. Active participation in scientific and research projects.					
Grade (maximum number of points 100)					
Pre-exam duties		Points	Final exam		Points
Activity during lectures			Written exam		
Exercises			Oral exam		50
Colloquia					
Projects		50			